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Thorsten Lill is VP of Emerging Etch Technologies and Systems at Lam Research. He holds a Ph.D. in Physics from the Albert-Ludwigs-University in Freiburg, Germany.

In Freiburg, he studied collisions of C_{60} and C_{70} fullerenes with crystalline surfaces in ion and laser beam experiments. After his graduate studies, he spent time as a post doc researcher at the Chemistry Department at the Argonne National Laboratory working on sputtered metal cluster experiments with Secondary Neutral Mass Spectrometry with laser post ionization.

He has published over 130 articles and conference papers including first author articles in Physical Review Letters and Science and holds 62 granted patents in the fields of plasma and ion beam sources, plasma etching, Atomic Layer Etching, CVD, reactor design, and diagnostics.